

INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 1 OF 2		ATTY. DOCKET NO. P128-US		SERIAL NO. Not Yet Assigned			
		APPLICANT Jonathan Doan					
		FILING DATE Herewith		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
EC ↓	Published Patent App No. US2002/0132389 A1	09/19/02	Patel, et al.				
	Published Patent App No. US2003/0166342 A1	09/04/03	Chinn, et al.				
	Published Patent App No. US2003/0036215 A1	02/20/03	Reid				
	Published Patent App No. US2003/0124462 A1	07/03/03	Miller				
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	5,709,802	01/20/98	Furuhata, et al.				
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	✓	5,426,070	06/20/95	Shaw, et al.			
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						YES	NO
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EC ↓ ↓	S. Mubassar Ali, et al., USE OF THERMAL CYCLING TO REDUCE ADHESION OF OTS COATED MEMS CANTILEVERS, 2003, pp. 151-162.						
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<i>Eric Ann</i>			12/6/05				
EXAMINER			DATE CONSIDERED				

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EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
EC ↓	6,259,551B1	07/10/01	Jacobs				
	5,936,758	08/10/99	Fisher, et al.				
	5,939,785	08/17/99	Klonis, et al.				
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
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EC ↓	Uthara Srinivasan, et al., LUBRICATION OF POLYSILICON MICROMECHANISMS WITH SELF-ASSEMBLED MONOLAYERS, 1998, pp.156-161.						
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EXAMINER		<i>Eric Chun</i>		DATE CONSIDERED		<i>12/6/05</i>	

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INFORMATION DISCLOSURE CITATION APR 27 2005 PATENT & TRADEMARK SERVICE		ATTY. DOCKET NO. P128-US		SERIAL NO. 10/766,776			
		APPLICANT Doan, et al.					
		FILING DATE 1/27/04		GROUP Not Yet Assigned			
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EC ↓	5,939,785	8/17/99	Klonis, et al.				
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
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EC ↓	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICTION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.						
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EXAMINER		<i>C. Chen</i>		DATE CONSIDERED		12/6/05	

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EXAMINER <i>Eric Alm</i>				DATE CONSIDERED 12/6/05			

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